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ABSTRACT

A semiconductor manufacturing device (76) of a minienvironment system, in which system a wafer (73) is conveyed by a wafer hermetic container (71) to the semiconductor manufacturing device equipped with a wafer carrying-in opening (98), comprising a clean-air injection semiconductor manufacturing device (1) for forming a clean-air curtain between an opened opening (74) of the hermetic container and the wafer carrying-in opening to prevent ambient air from entering the opened opening (74) of the hermetic container when the hermetic container (71), which is located in front of the wafer carrying-in opening of the semiconductor manufacturing, is opened.